

ABSTRACT**Process for limiting the emissions of gases from porous particles**

A subject-matter of the present invention is a process for limiting the emissions of gases from a porous material in the form of particles comprising a porous inorganic support and at least 0.1% by weight of one or more compounds chosen from organic compounds, halogen compounds, boron compounds and phosphorus compounds. The particles are placed in motion within a hot gas stream traversing them, and a liquid composition containing one or more film-forming polymer(s) is sprayed over the moving particles by means of a twin-fluid atomization nozzle, in which the liquid composition is mixed with a pressurized gas, with a relative atomization pressure of greater than or equal to 0.7×10^5 Pa, until a protective layer containing the film-forming polymer(s) and exhibiting a mean thickness of less than or equal to 20 μm is obtained on the surface of the said particles.

Another subject-matter of the present invention is a material in the form of particles which are covered with a protective layer, which material is capable of being obtained by this process.

NO FIGURE.